HIGH ACCURACY PRESSURE TRANSDUCERS



SOLID STATE PIEZORESISTIVE DESIGNWITH HIGH TEMP. PERFORMANCE FOR INDUSTRY, AUTOMOTIVE, TEST, AND AEROSPACE APPLICATIONS

mV/V, 0 to 5 Vdc, 0 to 10 Vdc, 4 to 20 mA Outputs

Low Pressure: 10 inH₂0 and Standard Ranges: 5 to 5000 psi Metric Ranges: 25 mbar to 345 bars

Gage or Absolute Pressure

PX409 Series



High Accuracy ±0.08% BSL Includes Linearity, Hysteresis, and Repeatability

✓ Broad Temperature Compensated Range -29 to 85°C (-20 to 185°F)

✓ Premium Temperature Performance Span: ±0.5% Over Compensated Range

✓ 5-Point NIST Traceable Calibration Included

Digital Dynamic Thermal Compensation Across Temperature and Pressure Range

✓ Low Pressure Ranges from 10 inH₂O

✓ All Stainless Steel Wetted Parts

✓ Fast Response Time

✓ Solid State Reliability and Stability

Gage and Absolute Pressures

✓ 300% Proof Pressure Minimum

OMEGA piezoresistive pressure transducers have a proven record in high performance commercial and aerospace applications for over 25 years. The piezoresistive process uses strain gages molecularly embedded into a highly stable silicon wafer. The silicon wafer is diced into individual die which each contain a full strain gage bridge. The die is mounted in a sealed chamber protected from the environment by glass to metal seals and a stainless steel diaphragm.

A small volume of silicone oil transfers the pressure from the diaphragm to the strain bridge. The construction provides a very rugged transducer with exceptional accuracy, stability and thermal effects. A unique design ruggedizes the transducers by providing secondary fluid containment in the event of a diaphragm rupture.

At our state-of-the-art facilities, automated test equipment performs pressure and temperature cycling on 100% of the PX409 transducers. The transducers are then calibrated using extremely high accuracy equipment and a 5-point NIST traceable calibration certificate that is included with each transducer. To obtain their high accuracy and stability, the PX409 Series use state-of-the-art digital mapping of the temperature, pressure and output performance of the silicon sensor in conjunction with a custom ASIC to provide dynamic thermal compensation across the



PX409 SERIES SILICON WAFER TECHNOLOGY PX409 Series uses a highly stable silicon wafer which is

PX409 Series uses a highly stable silicon wafer which is micro-machined to precision tolerances and then has strain gages molecularly embedded into it.





temperature and pressure parameters. The inherent stability of the piezoresistive core provides excellent long term stability, repeatability and very low thermal effects at the price of much lower performance transducers. Standard features of the PX409 Series also include protective features built into the electronics and the pressure element. Reverse polarity, EMC, and power supply fluctuation protection are standard on all models. Intrinsically Safe and CSA ratings are optional.

The most popular ranges and configurations are stocked for immediate delivery. All others typically have a very short lead-time.